

This Page Is Inserted by IFW Operations  
and is not a part of the Official Record

## **BEST AVAILABLE IMAGES**

Defective images within this document are accurate representations of the original documents submitted by the applicant.

Defects in the images may include (but are not limited to):

- BLACK BORDERS
- TEXT CUT OFF AT TOP, BOTTOM OR SIDES
- FADED TEXT
- ILLEGIBLE TEXT
- SKEWED/SLANTED IMAGES
- COLORED PHOTOS
- BLACK OR VERY BLACK AND WHITE DARK PHOTOS
- GRAY SCALE DOCUMENTS

**IMAGES ARE BEST AVAILABLE COPY.**

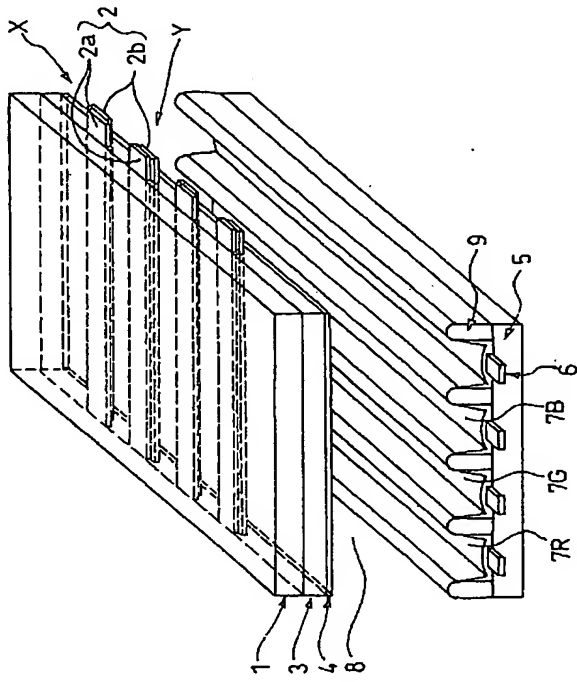
**As rescanning documents *will not* correct images,  
please do not report the images to the  
Problem Image Mailbox.**

~~【書類名】 図面~~

~~【図1】~~

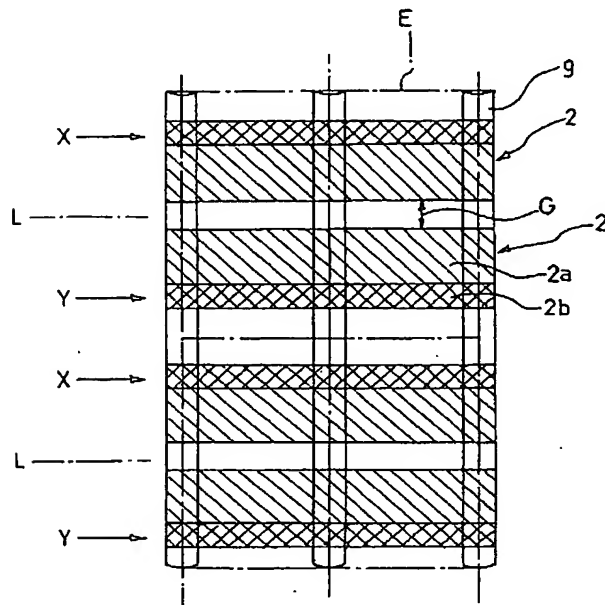
Junji KOGURE et al.  
PLASMA DISPLAY PANEL MANUFACTURING  
METHOD....  
Filing date: December 16, 2003  
Darryl Mexic 202-663-7909  
Page 1 of 8

Fig. 1 Prior Art



~~図2~~ Fig. 2

~~従来技術~~ Prior Art



~~図3~~ Fig. 3

~~従来技術~~ Prior Art

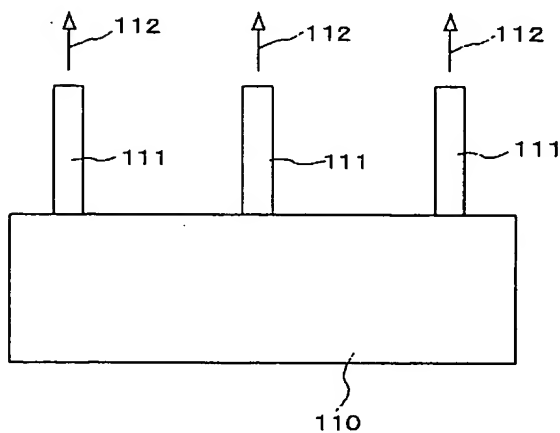
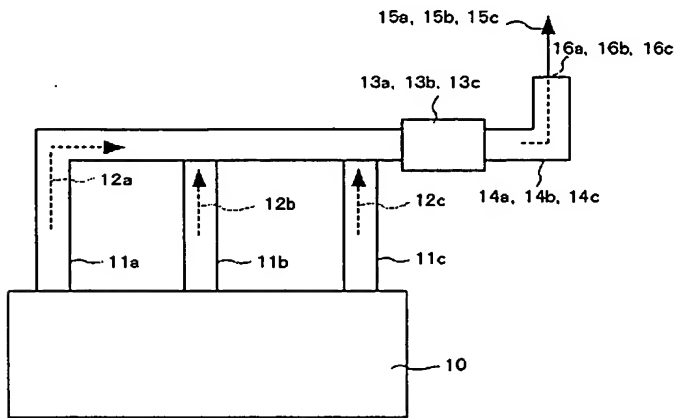
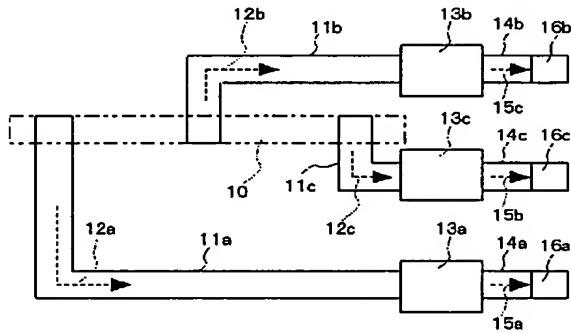


図 4 Fig. 4



Junji KOGURE et al.  
PLASMA DISPLAY PANEL MANUFACTURING  
METHOD....  
Filing date: December 16, 2003  
Darryl Mexic 202-663-7909  
Page 3 of 8

図 5 Fig. 5



~~図6~~

Fig. 6

Junji KOGURE et al.  
PLASMA DISPLAY PANEL MANUFACTURING  
METHOD....  
Filing date: December 16, 2003  
Darryl Mexic 202-663-7909  
Page 4 of 8

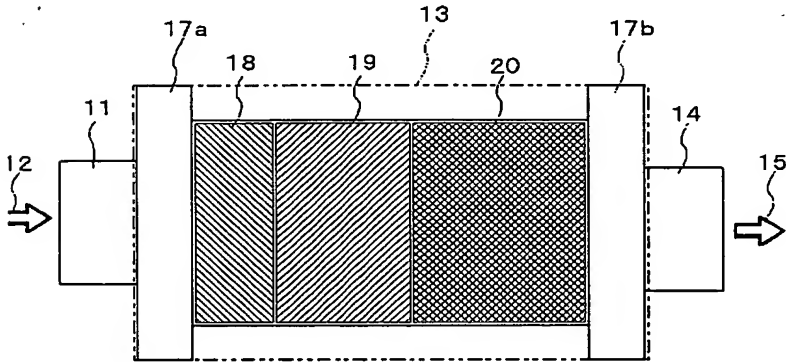
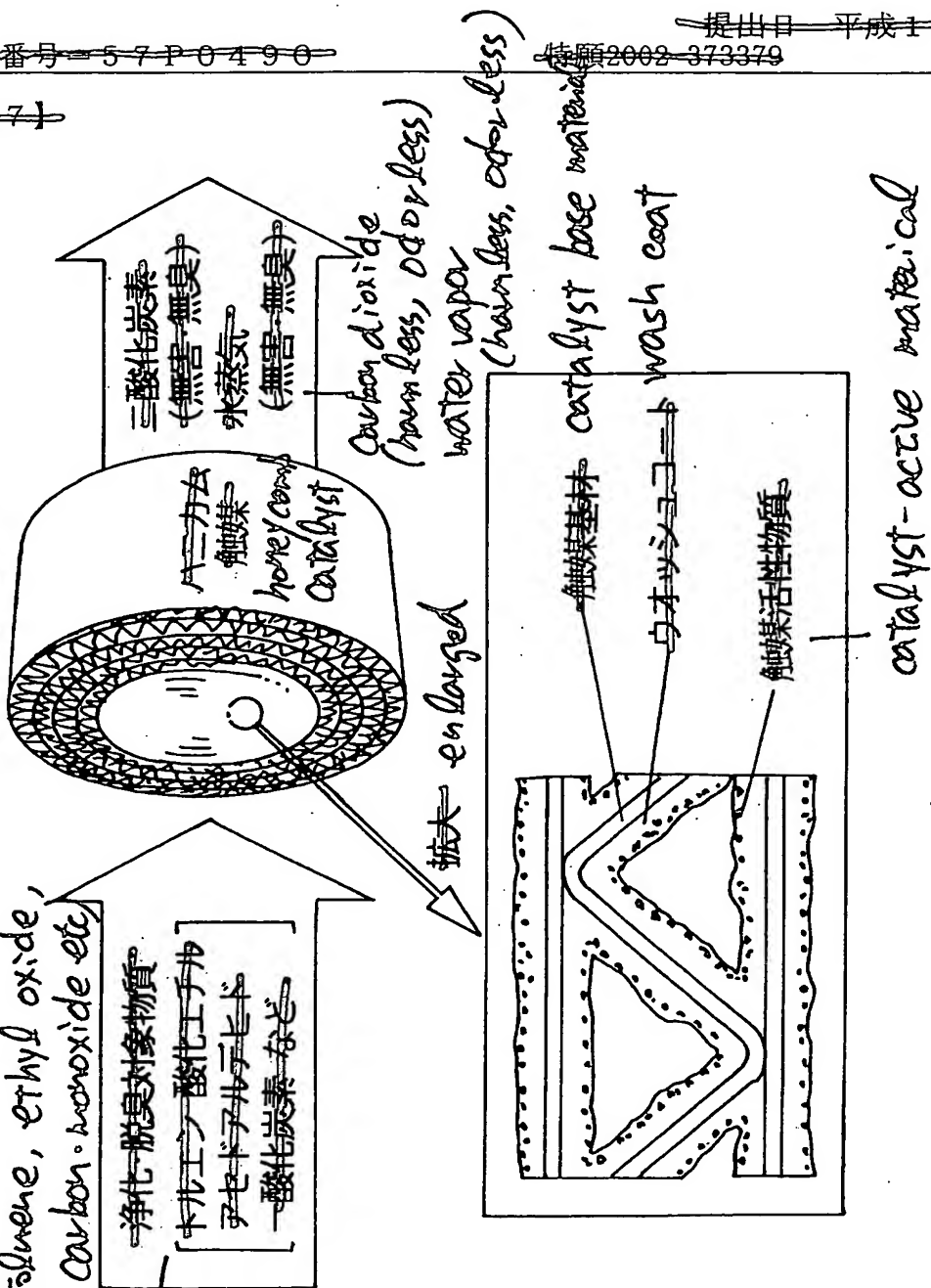


Fig. 7

purification/deodorization target  
substances (toluene, ethyl oxide,  
acetaldehyde, carbon monoxide etc.)

heat to predetermined temperatures

所定温度に加熱



整理番号 57P0490

提出日 平成14年12月25日

特許 2002-373379

頁 6/7

Fig. 8(a)

purification properties of metal honeycomb catalyst  
メタルハニカム触媒の浄化特性

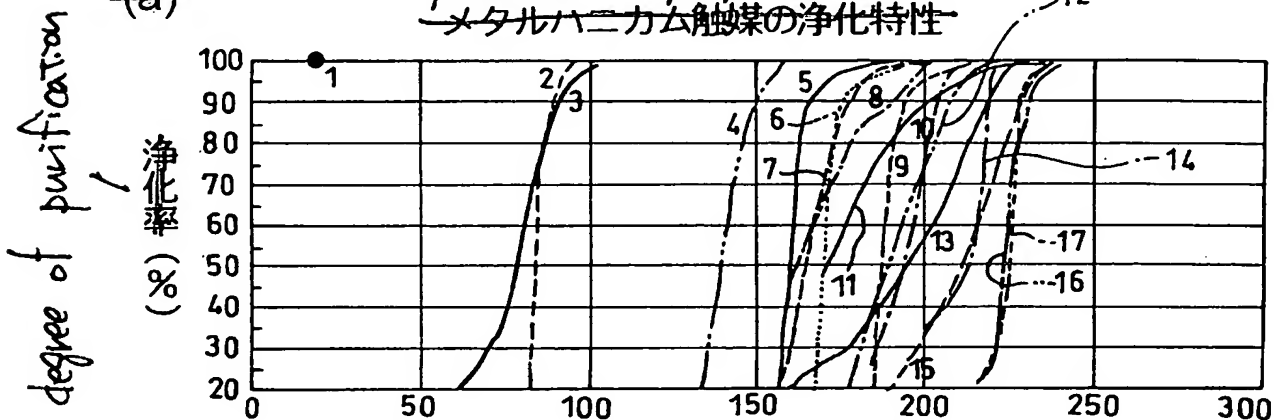


Fig. 8(b)

触媒入口ガス温度(°C)

catalyst inlet gas temperature

chemical formula

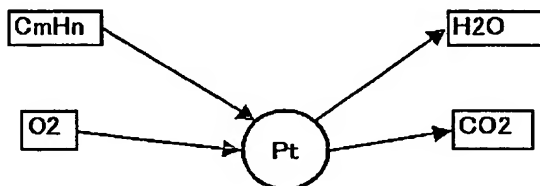
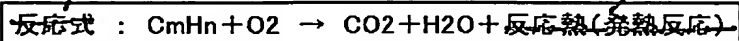
concentration

space velocity

No.	substance name 物質名	化学式	濃度 (ppm)	空間速度 (h <sup>-1</sup> )
1	<del>水素</del>	H <sub>2</sub>	1%	60,000
2	<del>酸化炭素</del>	CO	1,000	60,000
3	<del>メチルアルコール (水蒸気7.4%)</del>	CH <sub>3</sub> OH	100	30,000
4	<del>エチレン</del>	C <sub>2</sub> H <sub>4</sub>	5,000	60,000
5	<del>シクロヘキサノン</del>	C <sub>6</sub> H <sub>10</sub> O	550	60,000
6	<del>トルエン</del>	C <sub>6</sub> H <sub>5</sub> CH <sub>3</sub>	550	60,000
7	<del>メチルエチルケトン (MEK)</del>	C <sub>2</sub> H <sub>5</sub> COCH <sub>3</sub>	650	60,000
8	<del>二硫化メチル (DMG) (水蒸気7.4%)</del>	(CH <sub>3</sub> ) <sub>2</sub> S	10	30,000
9	<del>キシレン</del>	C <sub>6</sub> H <sub>4</sub> (CH <sub>3</sub> ) <sub>2</sub>	550	60,000
10	<del>アンモニア (水蒸気7.4%)</del>	NH <sub>3</sub>	300	30,000
11	<del>トリメチルアミン (水蒸気7.4%)</del>	(CH <sub>3</sub> ) <sub>3</sub> N	30	30,000
12	<del>アセトアルデヒド (水蒸気7.4%)</del>	CH <sub>3</sub> CHO	140	30,000
13	<del>エチルアルコール</del>	C <sub>2</sub> H <sub>5</sub> OH	300	30,000
14	<del>タリナールフェノール</del>	CH <sub>3</sub> C <sub>6</sub> H <sub>4</sub> OH + C <sub>6</sub> H <sub>5</sub> OH	660+440	60,000
15	<del>トリエチルアミン</del>	(C <sub>2</sub> H <sub>5</sub> ) <sub>3</sub> N	300	30,000
16	<del>酢酸 (水蒸気7.4%)</del>	CH <sub>3</sub> COOH	100	30,000
17	<del>ジメチルホルムアルデヒド</del>	HCON(CH <sub>3</sub> ) <sub>2</sub>	740	60,000

~~図9~~ **Fig. 9**  
reaction formula

reaction heat (exothermal reaction)



~~反応熱による温度上昇(1000ppm濃度力ス燃焼) = 10 + 20 \times C(炭素)数 [°C]~~

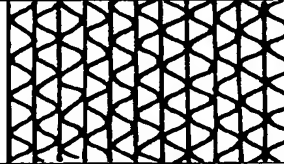
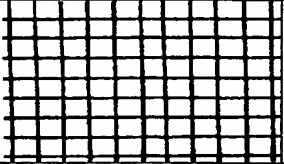
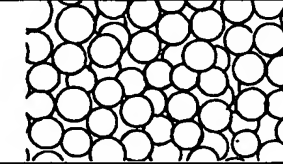
temperature rise  
resulting from  
reaction heat

(1000 ppm concentration  
gas combustion)

number  
carbon

**FIG. 10**

**Comparison of Properties of Various Catalysts**

Catalyst Type	Metal Honeycomb Catalyst	Ceramic Honeycomb Catalyst	Pellet Catalyst
Catalyst Type			
Basic Composition	Fe-Cr-Al	SiO <sub>2</sub> -Al <sub>2</sub> O <sub>3</sub> -MgO	γ-Al <sub>2</sub> O <sub>3</sub>
Coefficient of Heat Conductivity	Large	Small	Small
Filled Specific Gravity	0.4 to 0.6	0.6 to 0.7	0.4 to 0.8
Heat Capacity	Small	Moderate	Large
Standard SV Value	30,000 to 60,000 h <sup>-1</sup>	20,000 to 40,000 h <sup>-1</sup>	10,000 to 30,000 h <sup>-1</sup>
Pressure Loss (*)	5.5	7.1	41.5
Mechanical Strength	Strong	Weak	Moderate
Thermal Shock Resistance	Strong	Weak	Moderate

(\*: Measured value under an atmosphere of 200°C and 1 Nm/s.)